

The model CPS-150-LN2/LHe-HV enables cost effective, stable, reliable and convenient probing of the full 100mm or 150mm wafers at very low temperatures at improved vacuum levels. Built-in vibration isolation, smart thermal management, and use of low outgassing materials in combination with improved sealing makes this system ideally suited for a range of applications where better vacuum levels are needed, such as graphene research, molecular electronics, etc. The system uses proprietary thermal management permitting low cryogen consumption and fast operations. Built-in vibration isolation minimizes the vibrations to industry-standard levels. Ultra-stable micro-manipulated stages permit accurate and reproducible contact of the probe tip on device features.

Key Features

- Cost- effective, stable, reliable, and convenient to use for up to 150mm diameter wafers
- Temperature range from 4.5K to 470K (0.1K or better accuracy and stability, better than 50mK stability at below 250K)
 - Compatible with either LN2 or LHe cooling
- DC to 110GHz measurements with proper probes selected
- 4 micromanipulated probe arms (up to 8 available in optional configurations), with highly accurate XYZ and optionally θ adjustment, with up to 4" X, 1³/₄" Y and 0.5"Z
- Thermally anchored probe tips
- Temperature- controlled radiation shield
- Improved vacuum rating of the components
- Clear view large top window (high purity quartz)
- High frequency vibration damping
- High level of customization to accommodate most exotic probing needs
- Motorized XY, XYZ or XYZ[®] chuck positioning adjustments are available as optionalswith different ranges and resolutions



Specifications :	
Chuck size	
	- 175mm D, up to 3 auxiliary chucks can be installed
Thermal specifications Vacuum	 Liquid nitrogen or liquid helium cooled. Temperature range: 5K to 480K are available Temperature accuracy: 0.1K Temperature stability: ±50 mK below 250K Temperature resolution: 0.001K Thermally anchored probe arms and radiation shield Temperature controlled (heater) chuck Temperature monitoring of the chuck and probe arm Temperature monitoring of radiation shield is optional
	 Base pressure better 1.0 x 10⁻⁵ torr standard with all components at room temperature with proper vacuum pump selected, down to sub-10⁻⁷ torr optional with all components at room temperature Gas port and pressure relief valve are included in base system
Optics	
Microscope:	 Additional viewports: can be added by customer request Window materials: fused silica or quartz, custom materials and coatings are available
Cameras:	 Qioptiq's Optem Zoom 70 system (4um resolution) is standard, Zoom 125 or zoom 160 system are available as options, as well as less expensive solutions Coaxial and ring light LED illumination Optional cooled shutter Either boom mounted or with base mounted on fine resolution XY or XYZ slides
	 Digital cameras ranging from 1 megapixel to 10 megapixels. Included with the camera is software for image and video capture as well as dimension measurement capability

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<u>www.microxact.com</u> Phone: 540-394-4040 Fax: 1-866-588-0908

Specifications (cont.):	
Probes	 DC (coaxial or triaxial) RF (various)
Micromanipulators	 Various resolutions (40TPI or 3μm is standard, better resolution is available with extra cost) and ranges (2"x1"x0.5", 4"x1"x0.5" or 4"x1.75' x 0.5")available
Cables available	 Cryogenic temperature- compatible coaxial cables Cryogenic temperature-compatible triaxial cable Cryogenic RF cables Cryogenic non-magnetic RF cables
Wafer chucks available	 Grounded Isolated Coaxial Triaxial
Software	- LabView-based open-souice software
Vibration isolation	 Vibration isolation table with air damping system

- Vibration- isolating bellows Vibrations at the chuck <30nm





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